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PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Ko et al.

Application No: 09/894,230

Filed: June 27, 2001

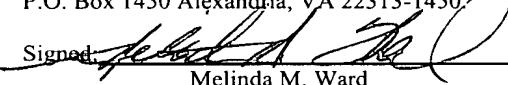
For: APPARATUS AND METHOD FOR ARGON  
PLASMA INDUCED ULTRAVIOLET LIGHT  
CURING STEP FOR INCREASING SILICON-  
CONTAINING PHOTORESIST SELECTIVITY



) Docket No: LAM2P257  
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CERTIFICATE OF MAILING

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Signed:   
Melinda M. Ward

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AMENDMENT

Commissioner for Patents  
Washington, D.C. 20231

Dear Sir:

This Communication is in response to the Office Action dated March 3, 2003.  
Please amend the application as follows:

Amendments to the Specification begin on page 2 of this paper.

Amendments to the claims are reflected in the listing of claims which begins on page 4 of  
this paper.

Amendments to the drawings begin on page 7 and include attached replacement sheets.

Remarks/Arguments begin on page 8 of this paper.